

NILindustrialday 2022

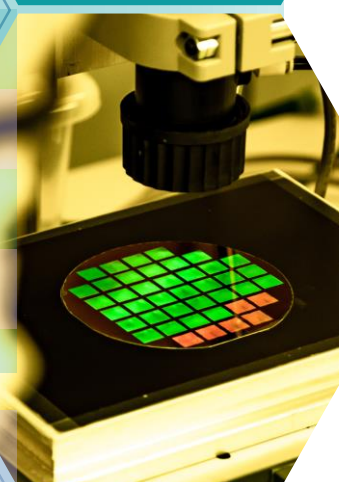
June 14 and 15

TENTATIVE
PROGRAM
FOR THE

VIRTUAL
EVENT

Day 1 – June 14

CEST	Affiliation	Speaker	Title
12:30			Online arrival of participants
13:00			Welcome
Session 1 chair: Jan Stensborg			
13:10	NILT	Theodor Nielsen	A selfie of invisible me
13:30	Tokyo University of Science	Jun Taniguchi	Advanced moth-eye structure film fabrication process and new applications
13:50	Femtoprint	Rolando Ferrini	3D printing of glass micro-devices for advanced optics and photonics
14:10	micro resist technology	Arne Schleunitz	Material sustainability for the NIL community
14:30			break
Session 2 chair: Michael Mühlberger			
14:50	ams OSRAM	Martin Salt	Opportunities and risks for metalenses in mass production
15:10	SUSS MicroTec	Fabian Kloiber	High Resolution Quality Assessment of SMILE Imprints in HVM
15:30	EV Group	Christine Thanner	Nanoimprinted Wafer Level MetaOptics
15:50	PROFACTOR	Michael Haslinger	Nanoimprint of high aspect ratio nano-needle structures
16:10			break
Session 3 chair: Anja Haase			
16:30	Temicon	Oliver Humbach	Roll Nanoimprint of micro- and nanostructured films, sheets and glasses
16:50	SCIL nanoimprint solutions	Marc Verschuuren	SCIL: materials and production solutions for AR/VR, DOEs and meta-lenses
17:10	Morphotonics	Pim Veldhuizen	Roll-to-Plate Nanoimprint Lithography for Creating Large-Area Structured Surfaces
17:30	University of Massachusetts Amherst	James Watkins	Imprinting with Non-Traditional Materials: Hierarchical Metal Oxides, Carbons and Ceramics for Optical and Energy Devices
18:00			Online networking



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Day 2 – June 15

CEST	Affiliation	Speaker	Title
07:30			Online arrival of participants
08:00			Welcome
Session 4 chair: Nikos Kehagias			
08:10	POSTECH	Junsuk Rho	Scalable optical metasurfaces via nanoparticle-embedded resin (nano-PER) printing
08:30	Hoya	Donna Qin	To shed & share more light for the upcoming “metaverse” world: HOYA’s potential solutions for NIL industry
08:50	Germanlitho	Ran Ji	NIL total solution for micro- and nano-optics in HVM
09:10	SONY	Christophe Peroz	Will NIL technology become the leading technology to fabricate nanophotonics devices
09:30			break
Session 5 chair: Gabi Grützner			
09:50	Fraunhofer IOF	Ulrike Schulz	Nanostructured AR-coatings for micro optics
10:10	NT&D	Boris Vratzov	UV-NIL in the Nanoworld. Processing and realized applications
10:30	AMO	Benny Ku	A Photocatalytic Panel for Solar Fuel Generation based on Plasmonic Nanodisc Arrays
10:50	IMS-Chips	Mathias Kaschel	Integrated photonics for sensing applications
11:10			break
Session 6 chair: Helmut Schiff			
11:30	Microfluidics innovation hub	Ronald Tingl	We get Microfluidics rolling
11:50	Phabuloµs	Jessica van Heck	Collaboration as USP for the manufacturing of free-form micro-optical components
12:10	cea leti	Jérôme Rêche	Reduction and stabilization of wafer scale nanoimprint lithography distortions
12:30	imec	Kristof Lodewijks	Plasmonic multispectral color filters by self-aligned nano-imprinted gratings
12:50			End of NILindustrialday 2022

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